

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L3	1630	269/21.ccls. or 279/3.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/03/24 08:48
L4	601	3 and (semiconductor or wafer or substrate)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/03/24 08:48
L5	505	3 and (semiconductor or wafer)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/03/24 08:48
L6	144	5 and (nitrogen or gas or inert)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/03/24 09:38
L9	4335	134/61,76,79,113,137,147,149,157,902.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/03/24 09:38
L10	237	9 and @pd>"20040625"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/03/24 09:39
L11	92	10 and (vacuum or suction)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/03/24 09:40
L12	146	156/345.15,345.16.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/03/24 09:39
L13	20	12 and @pd>"20040625"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/03/24 09:39
L14	8	13 and (vacuum or suction)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/03/24 09:40